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**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**

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Complete if Known

Application Number	National Stage Entry of PCT/JP2004/004938
Confirmation Number	Not yet assigned
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First Named Inventor	Yasuki KIMURA
Art Unit	Not yet assigned 1763
Examiner Name	Not yet assigned Olsen
Attorney Docket Number	Q87054

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U.S. PATENT DOCUMENTS

Examiner Initials*	Cite No. ¹	Document Number		Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document
		Number	Kind Code ² (if known)		
AK		US 5,976,986	A	11/2/1999	Naeem et al.
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FOREIGN PATENT DOCUMENTS

Examiner Initials*	Cite No. ¹	Foreign Patent Document			Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Translation ⁶
		Country Code ³	Number ⁴	Kind Code ⁵ (if known)			
AK		JP	2001-183809	A	7/6/2001	NEC CORP.	Abstract
		JP	01-149425	A	6/12/1989	The Japan Steel Works, Ltd.	Abstract
		JP	10-107013	A	4/24/1998	International Business Machines Corp.	Abstract
		JP	09-279367	A	10/28/1997	Mitsubishi Electric Corp.	Abstract
		JP	2001-135617	A	5/18/2001	Sony Corp.	Abstract
		JP	07-094468	A	4/7/1995	Fujitsu Ltd.	Abstract

NON PATENT LITERATURE DOCUMENTS

Examiner Initials*	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city, and/or country where published.	Translation ⁶
AK		JAMES A. REYNOLDS, et al., Proceedings of SPIE: 17 TH Annual Symposium on Photomask Technology and Management, 17-19 September 1997, Volume 3236, pp. 94-103	
		HIDEO SUGAI, Production and Physics of High Density Plasmas, Journal of Sputtering & Plasma Processes, Vol. 13, No. 4, October 9, 1998, Japan	

Examiner Signature

Allan Olsen

Date Considered

3-20-06

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